

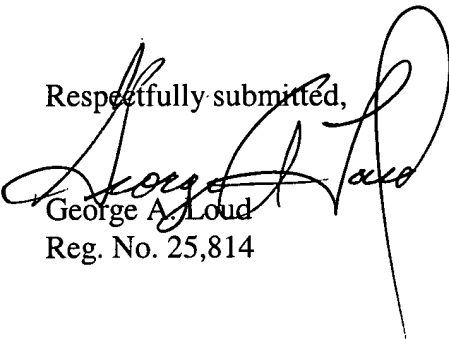
applicants' claim 1 on Bacchi et al, the examiner did so in a manner contrary to the applicants' intended meaning of certain claim language. More specifically, it is noted that the examiner would read both applicants' "port door horizontal-movement mechanism" and applicants' "sensor horizontal-movement mechanism" on a single element of the apparatus disclosed by Bacchi et al, i.e., "port door carriage mechanism 252" of Bacchi et al. On the contrary, applicants' intent was to claim structure wherein the "port door horizontal-movement mechanism" and the "sensor horizontal-movement mechanism" are operative, at least in part, independently of each other. By way of example, note the separate drive motors 43 and 63 of the preferred embodiment shown in applicants' drawings. Accordingly, claim 1 has now been amended in accordance with the teaching at page 16, lines 20-22 and at page 17, lines 4-7 of applicants' original specification. Note that applicants' mechanism is intended to operate, with the port door and FOUP door open (removed), to insert the sensor into the FOUP and to withdrawn the sensor from the FOUP after a vertical scanning. Such a function would be impossible if the "sensor horizontal-movement mechanism" were not capable of operation independently of the "port door horizontal-movement mechanism." In contradistinction, in the structure of Bacchi et al, as shown in Figs. 13-15 and as described at column 8, lines 29-32 "a differential, transmissive optical scanning assembly (290)" is mounted in a recess near the top side of the port door (76). Accordingly, with the structure disclosed by Bacchi et al movement of the sensor independently of the port door is quite impossible.

The rejection of claims 4-6 for obviousness is traversed because claims 4-6 depend directly or indirectly from claim 1 and, therefore, recite the same patentable distinctions noted

above in connection with the traverse of the rejection of claims 1-3. The rejection of claims 4-6 for obviousness is further traversed for the reason that the teaching at column 6, lines 18-53 of Lane et al, on which the examiner relies, has reference to evacuation of a "load lock chamber" which would be equivalent to the FOUP referred to in applicants' claims and a transfer chamber which would be equivalent to the clean room referred to in applicants' claims. Lane et al does not provide a separate housing for drive mechanisms and, therefore, in no way suggests evacuation of such a housing.

In conclusion, it is respectfully requested that the examiner reconsider the rejections of record with a view toward allowance of the claims as amended.

Respectfully submitted,


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Dated: May 12, 2003

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DRIVE-SECTION-ISOLATED FOUP OPENER

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BACKGROUND OF THE INVENTION

Field of the Invention:

The present invention relates to a container opener for opening/closing a sealable container for containing and transferring a plurality of semiconductor wafers oriented horizontally and ^{vertically} arranged in layers at predetermined intervals. More particularly, the invention relates to a front opening unified pod (FOUP) opener having a structure such that a drive section for a port door including a detachment/attachment mechanism for detaching/attaching a FOUP door and a holder mechanism for holding the FOUP door, and a drive section for a sensor mechanism for detecting presence/absence, storage condition, and position of wafers contained in the FOUP are arranged in an improved manner.

Description of the Related Art:

A FOUP opener is adapted to establish communication between a space (a first control space) within a FOUP and a wafer transfer space (a second control space) and to enable transfer of wafers from the first control space to the second control space without exposure to the ambient atmosphere, by means of, for example, a robot. When the wafers are highly-precise wafers having a diameter of 300 mm or more, since such wafers are very expensive, the FOUP opener must satisfy a strict requirement ^{for protection} against wafer contamination with dust.

Specifically, dust particles generated by the FOUP opener

itself must be reduced to one particle/10 cft or less (0.1 μ m particles), and ^{the} mapping report error rate must be decreased to once/0.1-1 million wafers or ^{less} lower. In order to detect presence/absence, storage condition, or position of wafers contained in the FOUP before transfer of the wafers, mapping means is provided on either the FOUP opener or a robot. Generally, provision of the mapping means is optional for the FOUP opener and the robot.

FIG. 5 shows a conventional FOUP opener. As shown in FIG. 5, operation of a FOUP opener 01 for detaching a FOUP door 013 from and attaching the FOUP door 013 to ^{from} an opening portion of a FOUP 010 and for moving the FOUP door 013 vertically is performed within a second control space 200 that maintains a clean room atmosphere. Accordingly, a drive section of a horizontal-movement mechanism 040 for moving a port door 023 and a sensor 070 horizontally and a drive section of a vertical-movement mechanism 050 for moving the port door 023 and the sensor 070 vertically are disposed within the second control space 200 ^{The} and the port door 023 includes a detachment/attachment mechanism for detaching/attaching the FOUP door 013 and a holder mechanism for holding the FOUP door 013 (see Japanese Patent Application Laid-Open (kokai) No. 11-145244). Reference numeral 014 denotes a semiconductor wafer, reference numeral 021 denotes a port plate, and reference numeral 300 denotes ^{the} an ambient atmosphere.

Thus, there has been ^{the} a problem such that the drives

[sections], which are dust generation^{ors} ~~sources~~, contaminate the second control space 200, which must maintain a clean atmosphere. For example, when a movable member is actuated by a motor or cylinder of a drive section, friction causes generation of dust, which is scattered within a clean room (the second control space 200). Also, an organic substance generated through vaporization of a ~~smoother or~~ lubricant applied to a movable member^{may be} ~~is~~ scattered within the clean room 200. As a result, the clean room 200 fails to maintain a high level of cleanliness. Furthermore, when the drive sections are to be ~~subjected~~^{served for} to service work, such as maintenance, inspection, or repairs, within the clean room 200, a worker must move or remove equipment in order to establish work space within the clean room 200, resulting in scattering of dust within the clean room 200. Thus, restoration of cleanliness within the clean room 200 to a regular, high level consumes a considerably great amount of time and ~~involves incurrence of~~ cost. In order to enable a worker to work within the clean room 200, equipment for removing dust from the worker must be installed, thus ~~again~~ ^{ing further} ~~involving~~ ~~incurrence of~~ cost.

In order to cope with the above problem, a FOUP opener as shown in FIG. 6 has been proposed (see Japanese kohyo (PCT) Patent Published (re-published) No. WO99/28965). As shown in FIG. 6, a port door is disposed outside a clean room (a second control space 200) ~~so as to carry out~~^{for} opening/closing and vertical movement of a FOUP door outside

the clean room 200. However, since a port door 023 is located between a FOUP 010 and a port plate 021, a gap g is formed therebetween. The gap g ^{creates the possibility of} involves possible entry of dust into the FOUP 010 (first control space 100) and ^{into} the clean room 200 from outside the clean room 200 (from ^{the} [an] ambient atmosphere 300), possible adhesion of the dust to the inside surface of [a] FOUP door 013 and ^{to} the outside surface of the port door 023, and possible outflow of a large amount of highly clean air to the exterior of the clean room 200.

In the case of the FOUP opener 01 of the patent publication, ^{as the gap g} [the distance] between the FOUP 010 and the port plate 021 becomes [long] (the gap g becomes [large]). ^{Thus when} the positioning accuracy of the FOUP 010 ^{is reduced} deteriorates due to machining errors, assembly errors, and wear of [a] dock plate 031 for carrying and positioning the FOUP 010 and components of [a] dock moving mechanism 030. ^{for moving the dock plate 031} [to the position of detachment/attachment of the FOUP door 013,] ^{Thus, the} presence/absence, storage condition, and position of wafers 014 contained in the FOUP 010 cannot be detected ^{with} at high accuracy, thus ^{creating} [causing] a possible problem in transfer of the wafers 014.

SUMMARY OF THE INVENTION

An object of the present invention is to solve the above-mentioned problems in the conventional FOUP openers and to provide a FOUP opener which does not ^{cause} [involve] contamination of a clean room (a second control space) ^{by} [with] contaminants

generated by drive⁵ sections of horizontal- and vertical-
movement mechanisms for a port door and a sensor; which does
not^{allow} involve entry of dust into a FOUP (first control space)
or into [and] the clean room from outside the clean room (an) ambient
atmosphere. ^{Another object is to prevent} [and] adhesion of [the] dust to the inside surface
of a FOUP door and^{to} the outside surface of the port door² [i]
^{Yet another object is to prevent} [which does not involve outflow of a large amount of highly
clean air to the exterior of the clean room² and which does
^{is to reduce the gap} not involve a long distance^{of} between the FOUP and a port plate,
to thereby avoid impairment [in] accuracy in positioning of the
FOUP due to machining errors, assembly errors, and wear of a
dock plate and components of a dock moving mechanism, so that
a mapping sensor can maintain high detection accuracy to
[thereby] avoid [a] possible problem⁵ in transfer of^{the} wafers.

To achieve the above object⁵, the present invention
provides a drive-section-isolated FOUP opener for opening and
closing a FOUP door which closes a front opening portion of a
FOUP containing a plurality of semiconductor wafers oriented
horizontally and^{vertically} arranged [in layers] at predetermined
intervals. The FOUP opener comprises a dock plate for
carrying and positioning the FOUP; a dock moving mechanism
for moving the dock plate to a position for detachment and
attachment of the FOUP door; a port door including a
detachment/attachment mechanism for detaching and attaching
the FOUP door and a holder mechanism for holding the FOUP
door; a port plate including an opening [portion], the opening
[portion] being closed by the port door; a port door

horizontal-movement mechanism for horizontally moving the port door; a sensor horizontal-movement mechanism for horizontally moving a sensor bracket, the sensor bracket having a mapping sensor mounted on an upper portion thereof and adapted to detect presence/absence, storage condition, and position of wafers contained in the FOUP; and a port-door-and-sensor vertical-movement mechanism for vertically moving the port door and the sensor bracket with the port door holding the FOUP door so as to house the FOUP door. A drive section of the port door horizontal-movement mechanism, a drive section of the sensor horizontal-movement mechanism, and a drive section of the port-door-and-sensor vertical-movement mechanism are disposed on the opposite side of relative [in opposition] to a clean room with respect to the port plate, with the clean room housing the port door and the sensor bracket.

Thus, in the drive-section-isolated FOUP opener of the present invention, the drive section of the port door horizontal-movement mechanism, the drive section of the sensor horizontal-movement mechanism, and the drive section of the port-door-and-sensor vertical-movement mechanism are disposed outside [in opposition to] the clean room (the second control space)—which houses the port door and the sensor bracket i. e. on the side of opposite the clean room and [with respect to] the port plate [to] thereby [be] isolated from the clean room.

As a result, the port plate prevents entry into the clean room of dust generated by [from] the drive sections. For example, when a movable member actuated by a motor or

cylinder of a drive section generates dust through friction, the dust is not scattered into the clean room. Also, an organic substance generated through vaporization of a [smoother or] lubricant applied to a movable member ^{does} [is] not enter [scattered into] the clean room. Furthermore, when the drive sections are to be [subjected to] service ^{work} ^{for} such as maintenance, inspection, or repairs, a worker ^{does} [does] not need [to] enter the clean room; i.e., the worker does not need to move or remove equipment in order to establish work space within the clean room, thereby avoiding contamination of the clean room with dust associated with such work. Therefore, the clean room can maintain a high level of cleanliness.

Since a worker does not need to enter the clean room when the drive sections are to be [subjected to] service ^{work} ^{for} such as maintenance, inspection, or repairs, there is no need to install equipment for removing dust from the worker who is to enter the clean room for performing service work, thereby lowering equipment expenses.

Since the port door is disposed within the clean room, the ^{gap} [distance] between the FOUP and the port plate can be ^{very small} [rendered] zero or [short]; thus, ^{Because} the gap therebetween ^{is} [becomes] very small, [thereby avoiding] entry of dust into the FOUP (first control space) and ^{into} the clean room from [outside] the clean room (an) ambient atmosphere ^{is avoided, along avoidance of}, [and] adherence of the dust to the inside surface of the FOUP door and the outside surface of the port door as well as outflow of a large amount of highly clean air ^{from} [to the exterior of] the clean room. Thus,

more reliably
the clean room can^v maintain a high level of cleanliness, [in a]
[more reliable condition.]

Furthermore, since the gap between the FOUP and the
port plate ^{is} [becomes very] small, [impairment] [in accuracy] in
positioning of the FOUP due to machining errors, assembly
errors, and wear of the dock plate and components of the dock
moving mechanism can be avoided. Thus, the mapping sensor
can maintain high detection accuracy, so that wafers can be
transferred ^{with} [at] high reliability.

vertically extending
Preferably, the port plate has a guide slit located
underneath ^{its} [the] opening [portion] in a [downwardly extending]
[condition], and the drive section of the port door horizontal-
movement mechanism, the drive section of the sensor
horizontal-movement mechanism, and the drive section of the
port-door-and-sensor vertical-movement mechanism move the
port door and the sensor bracket horizontally or vertically,
via the guide slit.

Thus, entry of dust into the clean room through the
guide slit from outside the clean room and outflow of a large
amount of highly clean air to the exterior of the clean room
through the guide slit can be suppressed to the greatest
possible extent, thereby contributing to the maintenance of a
high level of cleanliness in the clean room. ^{Which arms} [Arms] of the
port door and sensor bracket move along the guide slit,
thereby [involving] possible ^{ing} generation [of] dust. [However], the
dust can be ejected to the exterior of the clean room from
the guide slit through employment of a clean room pressure (a

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positive clean room pressure) higher than ^a pressure outside the clean room. Thus, this feature also contributes to the maintenance of a high level of cleanliness in the clean room.

Preferably, the guide slit is used in common for moving the port door and the sensor bracket.

No. 10 ^Q Thus, the number of guide slits can be minimized to thereby enhance the aforementioned effects.

Preferably, the drive-section-isolated FOUP opener of the present invention further comprises a drive section chamber for housing the drive section of the port door horizontal-movement mechanism, the drive section of the sensor horizontal-movement mechanism, and the drive section of the port-door-and-sensor vertical-movement mechanism. The drive section chamber includes a device for exhausting ^{from} an atmosphere ⁱⁿ the drive section chamber to the exterior ^{of} the drive section chamber.

No. 11 ^Q Thus, entry of dust generated in the drive sections into the clean room through the guide slit can be completely prevented, thereby ^{more reliably} maintaining the clean room at a high level of cleanliness ^{in a more reliable condition}.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 is a schematic sectional view of a drive-section-isolated FOUP opener according to an embodiment of the present invention ^{with the} showing the FOUP opener in a state ^{closed} before a FOUP door ^{is} opened;

FIG. 2 is a schematic ^{rear} back view of the FOUP opener of

FIG. 1 as viewed with a drive section chamber wall removed;

FIG. 3 is a sectional view taken along line III-III of FIG. 2;

FIG. 4 is a schematic partial perspective view of the FOUP opener of FIG. 1 as viewed from the port door side;

FIG. 5 is a view of a conventional FOUP opener; and

FIG. 6 is a view of another conventional FOUP opener.

DESCRIPTION OF THE PREFERRED EMBODIMENT

An embodiment of the present invention will next be described in detail with reference to the drawings.

As shown in FIG. 1, a drive-section-isolated FOUP opener 1 of the present embodiment includes a FOUP 10 containing a plurality of semiconductor wafers 14 oriented horizontally and ^{vertically} arranged in layers at predetermined intervals; a dock plate 31 for carrying and positioning the FOUP 10; a dock moving mechanism 30 for moving the dock plate 31 to a position ^{for} ~~for~~ detachment/attachment of a FOUP door 13; a port door 23 including a detachment/attachment mechanism (not shown) for detaching/attaching the FOUP door 13 and a holder mechanism (not shown) for holding the FOUP door 13; a port plate 21 including an opening portion 22, the opening portion 22 being closed by the port door 23; a port door horizontal-movement mechanism 40 for horizontally moving the port door 23; a sensor horizontal-movement mechanism 60 for horizontally moving a sensor bracket 62, the sensor bracket 62 having a mapping sensor 70 mounted on an upper portion

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thereof, the mapping sensor 70 being operative to detect presence/absence, storage condition, and position of the wafers 14 contained in the FOUP 10; and a port-door-and-sensor vertical-movement mechanism 50 for vertically moving the port door 23 and the sensor bracket 62 with the port door 23 holding the FOUP door 13, so as to house the FOUP door 13 in a front end (a second control space 200).

The FOUP 10 assumes the form of a sealed container when a front opening portion 12 of a FOUP frame 11, serving as ^{the} a body of the FOUP 10, is closed by the FOUP door 13. The port plate 21 and the port door 23 ^{form part of a} partially constitute an ^{interfacing} interface wall ^{of} the front end configured to interface with the FOUP 10 and ^{serve} are adapted to isolate the second control space 200, which ^{serves} is configured as a clean room and serves as a wafer transfer space, from ^{the} an ambient atmosphere 300. As shown in FIG. 4, the sensor bracket 62 ^{has} assumes the form of a rectangular frame and is arranged in such a manner as to surround ^{the} the port door 23. and A lower extension member 42 extending ^{downward} downward from the port door 23 with a slight gap formed therebetween.

The port door horizontal-movement mechanism 40 is ^{includes an} configured in the following manner. An arm member 44 ^{which extends} is perpendicularly ^{from the} attached to a lower end portion of the lower extension member 42 extending downward from the port door 23. The arm member 44 ^{is rigidly mounted in a linear guide 41} is disposed on the upper surface of a vertical-movement platform 51 of the port-door-and-sensor vertical-movement mechanism 50, which will be described later.

[in a condition slidable along a linear guide 41]. An end [portion] of the arm member 44 is connected to an output shaft of a port door horizontal-movement mechanism drive motor 43, which ~~is operative to~~ ^{is} move the arm member 44 horizontally ⁽ⁱⁿ [the right-and-left direction] in FIG. 1). The arm member 44 extends through a guide slit 52 formed in the port plate 21 [in such a manner as to] ^{and in} extend downward from underneath an opening [portion] 22 ⁱⁿ of the port plate 21. The arm member 44 moves horizontally and vertically along the guide slit 52.

The sensor horizontal-movement mechanism 60 [is] ^{includes an} which [configured in the following manner. An] arm member 64 is perpendicularly attached to a lower end portion of the sensor ^{which is slidably mounted in a linear guide 61} bracket 62 and [disposed] on the lower surface of the vertical-movement platform 51 of the port-door-and-sensor vertical-movement mechanism 50, which will be described later. [in a] [condition slidable along a linear guide 61.] An end [portion] of the arm member 64 is connected to an output shaft of a sensor horizontal-movement mechanism drive motor 63, which [is] [operative to] move^s the arm member 64 horizontally. As in the case of the arm member 44, the arm member 64 extends through the guide slit 52 [while being located] underneath the arm member 44, and moves horizontally and vertically along the guide slit 52.

As shown in FIG. 2, the right-hand and left-hand vertical-movement platforms 51, arm members 44, and arm members 64 are ^{located adjacent} [located while being biased toward] the right-hand and left-hand side edges of the port plate 21. The

right-hand and left-hand vertical-movement platforms 51 are connected unitarily by means of a connection member 55 extending ^{horizontally} ~~in the right and left direction~~ in FIG. 2. The connection member 55 has a nut accommodating portion 56 ^{central} ~~which~~ ^{formed at a central portion along the right-and-left} ~~direction. The nut accommodating portion 56~~ houses a ball nut engaged with a screw shaft 54. As the screw shaft 54 is rotated by a servomotor 53, the nut accommodating portion 56 ~~which houses the ball nut engaged with the screw shaft 54~~ is caused to move vertically; i.e., the connection member 55 ^{with} ~~whose~~ integral ~~portion is~~ the nut accommodating portion 56 moves vertically. The vertical movement of the connection member 55 causes the port door 23 and the sensor bracket 62 to move vertically as a unit via the paired vertical-movement platforms 51, arm members 44, and arm members 64.

As shown in FIGS. 2 and 3, the connection member 55 moves vertically along the outside surface of the port plate 21 while being guided by ^a ~~the following~~ guide mechanism ^{including} ~~guide grooves 58~~ ^{which} are formed in the corresponding right-hand and left-hand vertical-movement platforms 51 ^{in turn} ~~which~~ are connected unitarily by means of the connection member 55 ^{and} ~~which receive~~ ^{Guide rails 57} ~~fitted to~~ corresponding guide rails 57, ~~which are fixedly~~ ^{provided} on the outside surface of the port plate 21 ^{while} ~~being biased toward~~ ^{adjacent} the right-hand and left-hand side edges of the port plate 21 and extending ^{ing} vertically.

The port door horizontal-movement mechanism drive motor 43 is fixedly ^{provided} on the upper surface of the right-hand

vertical-movement platform 51 of FIG. 2, whereas the sensor horizontal-movement mechanism drive motor 63 is fixed^{ly} ^{provided} on the lower surface of the left-hand vertical-movement platform 51 of FIG. 2. Thus, through installation of the port door horizontal-movement drive motor 43 and the sensor horizontal-movement drive motor 63 ^{horizontally} in opposition to each other ~~in the right-and-left direction of FIG. 2~~, weight balance is established ^{horizontally} ~~in the right-and-left direction~~ for a unitary assembly composed of the connection member 55, paired right- and left-hand vertical-movement platforms 51, and the motors 43 and 63. However, the motors 43 and 63 may be fixed^{ly} ^{provided} on the upper and lower surfaces, respectively, of the right-hand or left-hand vertical-movement platform 51.

The servomotor 53, the screw shaft 54, the connection member 55 including the nut accommodating portion 56, and the paired vertical-movement platforms 51 constitute the port-door-and-sensor vertical-movement mechanism 50. As shown in FIGS. 1 and 2, the port-door-and-sensor vertical-movement mechanism 50 is ^{on the side of the port plate 21 opposite} ~~disposed in opposition to~~ the clean room (the second control space 200) ~~which houses the port door 23 and the sensor bracket 62~~ ^{and is} ~~with respect to the port plate 21~~ ^{while being} housed in a drive section chamber 80.

Since the port-door horizontal-movement mechanism drive motor 43 and the sensor horizontal-movement mechanism drive motor 63 are fixed^{ly} ^{provided} on the right- and left-hand vertical-movement platforms 51, respectively, the motors 43

and 63 are also housed in the drive section chamber 80. Also, the drive section chamber 80 houses portions of the arm members 44 of the port door horizontal-movement mechanism 40 which slide along the linear guide 41 and portions of the arm members 64 of the sensor horizontal-movement mechanism 60 which slide along the linear guide 61.

Accordingly, the drive section (which is composed of the port door horizontal-movement mechanism drive motor 43 and the linear guide 41) of the port door horizontal-movement mechanism 40, the drive section (which is composed of the sensor horizontal-movement mechanism drive motor 63 and the linear guide 61) of the sensor horizontal-movement mechanism 60, and the drive section (which is composed of the servomotor 53, the screw shaft 54, the connection member 55 including the nut accommodating portion 56, and the paired right- and left-hand vertical-movement platforms 51) of the port-door-and-sensor vertical-movement mechanism 50 are disposed ^{opposite} in opposition to the clean room 200 which houses the port door 23 and the sensor bracket 62 with respect to the port plate 21 ^{and are} to thereby ^{be} isolated from the clean room 200 while ^{being} housed in the drive section chamber 80.

The drive section chamber 80 is equipped with a fan 81 for exhausting ^{the} an atmosphere ^{of} in the drive section chamber 80 to the exterior ^{of} the drive section chamber 80. ^{thus,} The fan 81 ^{is} operative to exhaust dust generated from the drive section of the port door horizontal-movement mechanism 40, the drive section of the sensor horizontal-movement mechanism 60, and

the drive section of the port-door-and-sensor vertical-movement mechanism 50, to the ambient atmosphere 300, thereby preventing contamination of the clean room 200 ^{by} with the dust. Preferably, the fan 81 is installed on a wall of the drive section chamber 80 at the lowest possible position.

Next, the operation of the drive-section-isolated FOUP opener 1 of the present embodiment will be described in detail.

^{As shown in}
In FIG. 1, the FOUP door 13 is about to be detached from the FOUP frame 11, and the port door 23 and the mapping sensor 70 are on standby. First, when the port door 23 vacuum-chucks and holds the FOUP door 13, the port door horizontal-movement mechanism 40 operates so as to ^{retract} retreat the port door 23 horizontally, which is not illustrated in detail. Then, the port-door-and-sensor vertical-movement mechanism 50 operates so as to lower the sensor bracket 62, together with the port door 23, to a position where the mapping sensor 70 is to be caused to enter the FOUP 10, thereby positioning the mapping sensor 70.

Next, the sensor horizontal-movement mechanism 60 operates so as to cause the mapping sensor 70 to enter the FOUP 10 independently of the port door 23. Subsequently, the port-door-and-sensor vertical-movement mechanism 50 operates so as to lower the mapping sensor 70, together with the port door 23, to the bottom wafer position. During the lowering movement, the mapping sensor 70 detects presence/absence, condition (inclined insertion, multiple insertion and other

items), and position (height) of the wafers 14 contained in the FOUP 10. The results of detection are transmitted ^{one by one} to an unillustrated wafer transfer robot one after another.

When the mapping sensor 70 lowers to the bottom wafer position, the sensor horizontal-movement mechanism 60 operates so as to ^{retract} retreat the mapping sensor 70 from inside the FOUP 10 independently of the port door 23. Finally, the port-door-and-sensor vertical-movement mechanism 50 operates so as to lower and ^{retract} retreat the port door 23 and the mapping sensor 70 in unison, thereby ^{holding} housing the FOUP door 13 in the front end ^{within} (the second control space 200).

The present embodiment ^{ing} is configured and functions as described above, thereby ^s yielding the following effects.

In the drive-section-isolated FOUP opener 1, the drive section of the port door horizontal-movement mechanism 40, the drive section of the sensor horizontal-movement mechanism 60, and the drive section of the port-door-and-sensor vertical-movement mechanism 50 are disposed in ^e opposition to the clean room (the second control space 200) which houses the port door 23 and the sensor bracket 62 with respect to the port plate 21 ^{and are} to thereby be isolated from the clean room 200. Thus, the port plate 21 prevents entry into the clean room 200 of dust generated ^{by} from the drive sections. For example, when a movable member actuated by a motor (the port door horizontal-movement mechanism drive motor 43, the sensor horizontal-movement mechanism drive motor 63, or the port door-and-sensor vertical-movement drive servomotor 53) of a

drive section generates dust through friction, the dust is not scattered into the clean room 200. Also, an organic substance generated through vaporization of a smoother or lubricant applied to a movable member is not scattered into the clean room 200. Furthermore, when the drive sections are to be subjected to service ^{for} work, such as maintenance, inspection, or repairs, a worker does not need to enter the clean room 200; i.e., the worker does not need to move or remove equipment in order to establish work space within the clean room 200, thereby avoiding contamination of the clean room 200 with dust associated with such work. Therefore, the clean room 200 can maintain a high level of cleanliness.

Also, since the port door 23 is disposed within the clean room 200, the distance between the FOUP 10 and the port plate 21 can be rendered zero or short; thus, the gap therebetween ^{is} becomes very small, thereby avoiding entry of dust into the FOUP 10 (the first control space 100) and ^{into} the clean room 200 from outside the clean room 200 (the ambient atmosphere 300), and adhesion of the dust to the inside surface of the FOUP door 13 and the outside surface of the port door 23, as well as ^{preventing} outflow of a large amount of highly clean air ^{from} to the exterior of the clean room 200. Thus, the clean room 200 can maintain a high level of cleanliness in a more reliable condition.

Furthermore, the port plate 21 has the guide slit 52 located underneath the opening portion 22 in a downwardly extending condition, and the drive section of the port door

horizontal-movement mechanism 40, the drive section of the sensor horizontal-movement mechanism 60, and the drive section of the port-door-and-sensor vertical-movement mechanism 50 move the port door 23 and the sensor bracket 62 horizontally or vertically, via the guide slit 52. Thus, entry of dust into the clean room 200 through the guide slit 52 from outside the clean room 200 and outflow of a large amount of highly clean air ^{from} ~~to the exterior of~~ the clean room 200 through the guide slit 52 can be suppressed to the greatest possible extent, thereby contributing to the maintenance of a high level of cleanliness in the clean room 200.

The arms 44 and 64 respectively connected to the port door 23 and sensor bracket 62 move along the guide slit 52 horizontally and vertically, thereby ^{creating the} ~~involving~~ possibility of generation of dust. However, the dust can be ejected to the exterior of the clean room 200 from the guide slit 52 through employment of a clean room pressure (a positive clean room pressure) higher than a pressure outside the clean room 200. Thus, this feature also contributes to the maintenance of a high level of cleanliness in the clean room 200.

Furthermore, since the right- and left-hand guide slits 52 are provided and used in common for moving the port door 23 and the sensor bracket 62, the number of guide slits 52 can be minimized to thereby enhance the aforementioned effects. Also, the drive section chamber 80 includes the fan 81 for exhausting ^{from} ~~an~~ atmosphere ~~in~~ the drive section chamber

80 to the exterior ^{by} of the drive section chamber 80. Thus, entry of dust generated ^{reliably} in the drive sections into the clean room 200 through the guide slits 52 can be completely prevented, thereby maintaining the clean room 200 at a high level of cleanliness in a far more reliable condition.

Also, since the gap between the FOUP 10 and the port plate 21 ^{is} becomes very small, impairment ^{of} in accuracy in positioning of the FOUP 10 due to machining errors, assembly errors, and wear of the dock plate 31 and components of the dock moving mechanism 30 can be avoided. Thus, the mapping sensor 70 can maintain high detection accuracy, so that the wafers 14 can be transferred ^{with} at high reliability.

Furthermore, since a worker does not need to enter the clean room 200 when the drive sections are to be subjected to service ^{for} work, such as maintenance, inspection, or repairs, there is no need to install equipment for removing dust from the worker who is to enter the clean room 200 for performing service work, thereby lowering equipment ^{cost} expenses.

The present invention is not limited to the above-described embodiment, but may be modified as appropriate without departing from the spirit or scope of the invention.

No. 11 → For example, the connection member 55 and the paired right- and left-hand vertical-movement platforms 51 may be connected in such a manner that the right- and left-hand vertical-movement platforms 51 are disposed on the upper or lower surface of the connection member 55 at right- and left-hand end portions thereof, while the guide groove 58 is

formed in each of right- and left-hand end portions of the connection member 55 and the right- and left-hand vertical-movement platforms 51. In this case, the vertical movement of the port-door-and-sensor vertical-movement mechanism 50 can be guided in a more reliable manner. Also, the individual drive sections may employ a power cylinder in place of the motor 43, 53, or 63, as an actuator.

ABSTRACT OF THE DISCLOSURE

A drive-section-isolated FOUP opener opens and closes a ~~[FOUP] door [which closes a front opening portion]~~ of a FOUP which contains a plurality of semiconductor wafers. The FOUP opener includes a dock plate for carrying and positioning the FOUP; a dock moving mechanism for moving the dock plate to a position for detachment/attachment of the FOUP door; a port door including a ~~[detachment/attachment]~~ mechanism for *releasably* ~~[detaching/attaching the FOUP door and a holder mechanism for]~~ holding the FOUP door; a port plate including an opening ~~[portion, the opening portion being]~~ closed by the port door; a port door horizontal-movement mechanism for horizontally moving the port door; a sensor horizontal-movement mechanism for horizontally moving a sensor bracket, the sensor bracket *carrying* ~~[having]~~ a mapping sensor ~~[mounted on an upper portion thereof];~~ and a port-door-and-sensor vertical-movement mechanism for vertically moving the port door and the sensor bracket with the port door holding the FOUP door^o, so as to house the FOUP ~~[door]~~. A drive^{So} ~~[section of]~~ the port door horizontal-movement mechanism, a drive^{So} ~~[section of]~~ the sensor horizontal-movement mechanism, and a drive^{So} ~~[section of]~~ the port-door-and-sensor vertical-movement mechanism are disposed ~~[in]~~ ^eopposition ~~[to]~~ a clean room ~~[which houses the port door and the sensor bracket]~~ with respect to the port plate.